

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	1	"6711775".pn.	USPAT	OR	OFF	2004/12/11 19:28
L2	22	("4062463" "4202071" "4382308" "5129955" "5144711" "5317778" "5351360" "5357645" "5361449" "5486134" "5490809" "5581837" "5624501" "5639311" "5651160" "5675856" "5693148" "5709755" "5778554" "5806126" "5875507" "6041465").PN. OR ("6711775").URPN.	US-PGPUB; USPAT; USOCR	OR	OFF	2004/12/11 19:39
L3	2	l2 and ph	US-PGPUB; USPAT; USOCR	OR	OFF	2004/12/11 19:41
L4	98	134/6.ccls. and 134/902.ccls.	US-PGPUB; USPAT; USOCR	OR	OFF	2004/12/11 20:03
L5	0	l4 and (through the brush)	US-PGPUB; USPAT; USOCR	ADJ	OFF	2004/12/11 19:42
L6	0	l4 and 'through the brush'	US-PGPUB; USPAT; USOCR	ADJ	OFF	2004/12/11 19:43
L7	17	l4 and brush and ph	US-PGPUB; USPAT; USOCR	ADJ	OFF	2004/12/11 19:49
L8	11	l4 and brush and rpm	US-PGPUB; USPAT; USOCR	ADJ	OFF	2004/12/11 19:49
L9	64	l4 and brush	US-PGPUB; USPAT; USOCR	OR	OFF	2004/12/11 20:03
L10	46	l4 and brush and rins\$	US-PGPUB; USPAT; USOCR	OR	OFF	2004/12/11 20:20
L11	6203	134/6.ccls. or 134/902.ccls. or 15/77.ccls. or 15/97.1.ccls. or 15/102.ccls. or 15/88.3.ccls.	US-PGPUB; USPAT; USOCR	OR	OFF	2004/12/11 20:26
L12	445	l11 and semiconductor and brush	US-PGPUB; USPAT; USOCR	OR	OFF	2004/12/11 20:56
L13	2	"5858109"	DERWENT	OR	OFF	2004/12/11 21:06
L14	1	1996wo-us16330	DERWENT	OR	OFF	2004/12/11 21:08
L15	1	1999wo-us20044	DERWENT	OR	OFF	2004/12/11 21:08

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	1	"6711775".pn.	USPAT	OR	OFF	2004/12/11 19:28
L2	22	("4062463" "4202071" "4382308" "5129955" "5144711" "5317778" "5351360" "5357645" "5361449" "5486134" "5490809" "5581837" "5624501" "5639311" "5651160" "5675856" "5693148" "5709755" "5778554" "5806126" "5875507" "6041465").PN. OR ("6711775").URPN.	US-PGPUB; USPAT; USOCR	OR	OFF	2004/12/11 19:39
L3	2	l2 and ph	US-PGPUB; USPAT; USOCR	OR	OFF	2004/12/11 19:41
L4	98	134/6.ccls. and 134/902.ccls.	US-PGPUB; USPAT; USOCR	OR	OFF	2004/12/11 20:03
L5	0	l4 and (through the brush)	US-PGPUB; USPAT; USOCR	ADJ	OFF	2004/12/11 19:42
L6	0	l4 and 'through the brush'	US-PGPUB; USPAT; USOCR	ADJ	OFF	2004/12/11 19:43
L7	17	l4 and brush and ph	US-PGPUB; USPAT; USOCR	ADJ	OFF	2004/12/11 19:49
L8	11	l4 and brush and rpm	US-PGPUB; USPAT; USOCR	ADJ	OFF	2004/12/11 19:49
L9	64	l4 and brush	US-PGPUB; USPAT; USOCR	OR	OFF	2004/12/11 20:03
L10	46	l4 and brush and rins\$	US-PGPUB; USPAT; USOCR	OR	OFF	2004/12/11 20:20
L11	6203	134/6.ccls. or 134/902.ccls. or 15/77.ccls. or 15/97.1.ccls. or 15/102.ccls. or 15/88.3.ccls.	US-PGPUB; USPAT; USOCR	OR	OFF	2004/12/11 20:26
L12	445	l11 and semiconductor and brush	US-PGPUB; USPAT; USOCR	OR	OFF	2004/12/11 20:27

D
Sa
D
12

PALM INTRANET

Ti
20**Inventor Name Search Result**

Your Search was:

Last Name = MIKHAYLICH

First Name = KATRINA

Application#	Patent#	Status	Date Filed	Title	Inventor Name 39
<u>60305372</u>	Not Issued	159	07/13/2001	DRYING A SUBSTRATE USING A COMBINATION OF SUBSTRATE PROCESSING TECHNOLOGIES	MIKHAYLICHENK KATRINA
<u>10880007</u>	Not Issued	020	06/28/2004	SYSTEM AND METHOD OF CLEANING AND ETCHING A SUBSTRATE	MIKHAYLICH, KATRINA
<u>10816487</u>	Not Issued	020	03/31/2004	PROXIMITY HEAD HEATING METHOD AND APPARATUS	MIKHAYLICHENK KATRINA
<u>10766733</u>	Not Issued	030	01/27/2004	METHOD AND SYSTEM FOR CLEANING A SEMICONDUCTOR WAFER	MIKHAYLICH, KATRINA A.
<u>10749983</u>	Not Issued	041	12/30/2003	END-POINT DETECTION APPARATUS	MIKHAYLICH, KATRINA A.
<u>10676830</u>	Not Issued	030	09/30/2003	METHOD APPARATUS AND CHEMICAL FOR REMOVING CU FILMS AND/OR RESIDUALS FROM WAFER FRONT	MIKHAYLICHENK KATRINA

				AND BACK	
<u>10662096</u>	<u>6827793</u>	150	09/12/2003	DRIP MANIFOLD FOR UNIFORM CHEMICAL DELIVERY	MIKHAYLICH, KATRINA A.
<u>10652648</u>	Not Issued	030	08/28/2003	METHOD AND APPARATUS FOR SIMULTANEOUSLY CLEANING THE FRONT SIDE AND BACK SIDE OF A WAFER	MIKHAYLICH, KATRINA
<u>10404403</u>	Not Issued	030	03/31/2003	CHEMICALLY ASSISTED MECHANICAL CLEANING OF MRAM STRUCTURES	MIKHAYLICHENK KATRINA
<u>10377944</u>	Not Issued	071	02/28/2003	BRUSH SCRUBBING-HIGH FREQUENCY RESONATING WAFER PROCESSING SYSTEM AND METHODS FOR MAKING AND IMPLEMENTING THE SAME	MIKHAYLICHENK KATRINA
<u>10328887</u>	<u>6733596</u>	150	12/23/2002	SUBSTRATE CLEANING BRUSH PREPARATION SEQUENCE, METHOD, AND SYSTEM	MIKHAYLICHENK KATRINA
<u>10196893</u>	Not Issued	071	07/16/2002	SYSTEM AND METHOD OF DEFECT OPTIMIZATION FOR CHEMICAL MECHANICAL PLANARIZATION OF POLYSILICON	MIKHAYLICH, KATRINA
<u>10196497</u>	<u>6770151</u>	150	07/15/2002	DRYING A SUBSTRATE USING	MIKHAYLICHENK KATRINA

				A COMBINATION OF SUBSTRATE PROCESSING TECHNOLOGIES	
<u>10186908</u>	Not Issued	094	06/28/2002	SUBSTRATE PROCESSING USING A FLUID RE- CIRCULATION SYSTEM IN A WAFER SCRUBBING SYSTEM	MIKHAYLICHENK KATRINA
<u>10186907</u>	Not Issued	041	06/28/2002	SYSTEM AND METHOD FOR A COMBINED CONTACT AND NON-CONTACT WAFER CLEANING MODULE	MIKHAYLICHENK KATRINA
<u>10186124</u>	Not Issued	083	06/28/2002	SYSTEM AND METHOD FOR ASYMMETRICAL RINSING AND CLEANING ONE OR BOTH SIDES OF A WAFER	MIKHAYLICHENK KATRINA
<u>10112639</u>	Not Issued	093	03/29/2002	IN-SITU LOCAL HEATING USING MEGASONIC TRANSDUCER RESONATOR	MIKHAYLICH, KATRINA
<u>10078941</u>	<u>6679763</u>	150	02/20/2002	APPARATUS AND METHOD FOR QUALIFYING A CHEMICAL MECHANICAL PLANARIZATION PROCESS	MIKHAYLICH, KATRINA
<u>10052769</u>	<u>6726530</u>	150	01/17/2002	END-POINT DETECTION SYSTEM FOR CHEMICAL MECHANICAL POLISHING APPLICATIONS	MIKHAYLICH, KATRINA A.

<u>10033644</u>	Not Issued	120	12/27/2001	METHOD FOR POST-ETCH AND STRIP RESIDUE REMOVAL ON CORAL FILMS	MIKHAYLICHENK KATRINA
<u>10017109</u>	6616516	150	12/13/2001	METHOD AND APPARATUS FOR ASYMMETRIC PROCESSING OF FRONT SIDE AND BACK SIDE OF SEMICONDUCTOR SUBSTRATES	MIKHAYLICH, KATRINA
<u>10013211</u>	Not Issued	093	12/07/2001	METHOD FOR CONTROLLING GALVANIC CORROSION EFFECTS ON A SINGLE-WAFER CLEANING SYSTEM	MIKHAYLICH, KATRINA A.
<u>10000494</u>	Not Issued	083	10/30/2001	METHOD AND SYSTEM FOR CLEANING A CHEMICAL MECHANICAL POLISHING PAD	MIKHAYLICH, KATRINA A.
<u>09823468</u>	Not Issued	161	03/30/2001	METHOD FOR PLANARIZING A SURFACE OF A SEMICONDUCTOR WAFER WITH A FIXED ABRASIVE MATERIAL	MIKHAYLICHENK KATRINA A.
<u>09752697</u>	6611326	150	12/27/2000	SYSTEM AND APPARATUS FOR EVALUATING THE EFFECTIVENESS OF WAFER DRYING OPERATIONS	MIKHAYLICHENK KATRINA
<u>09752609</u>	6521050	150	12/27/2000	METHODS FOR EVALUATING ADVANCED WAFER DRYING	MIKHAYLICHENK KATRINA

				TECHNIQUES	
<u>09678423</u>	<u>6800020</u>	150	10/02/2000	WEB-STYLE PAD CONDITIONING SYSTEM AND METHODS FOR IMPLEMENTING THE SAME	MIKHAYLICH, KATRINA A.
<u>09664609</u>	<u>6471566</u>	150	09/18/2000	SACRIFICIAL RETAINING RING CMP SYSTEM AND METHODS FOR IMPLEMENTING THE SAME	MIKHAYLICH, KATRINA
<u>09611235</u>	<u>6170110</u>	150	07/06/2000	APPARATUS FOR HF-HF CLEANING	MIKHAYLICH, KATRINA
<u>09608522</u>	<u>6435952</u>	150	06/30/2000	APPARATUS AND METHOD FOR QUALIFYING A CHEMICAL MECHANICAL PLANARIZATION PROCESS	MIKHAYLICH, KATRINA
<u>09608242</u>	<u>6375540</u>	150	06/30/2000	END-POINT DETECTION SYSTEM FOR CHEMICAL MECHANICAL POLISHING APPLICATIONS	MIKHAYLICH, KATRINA A.
<u>09607895</u>	<u>6361414</u>	150	06/30/2000	APPARATUS AND METHOD FOR CONDITIONING A FIXED ABRASIVE POLISHING PAD IN A CHEMICAL MECHANICAL PLANARIZATION PROCESS	MIKHAYLICH, KATRINA
<u>09538865</u>	<u>6622335</u>	150	03/29/2000	DRIP MANIFOLD FOR UNIFORM CHEMICAL DELIVERY	MIKHAYLICH, KATRINA A.
<u>09467460</u>	<u>6431959</u>	150	12/20/1999	SYSTEM AND METHOD OF DEFECT	MIKHAYLICH, KATRINA

				OPTIMIZATION FOR CHEMICAL MECHANICAL PLANARIZATION OF POLYSILICON	
<u>09408281</u>	<u>6537381</u>	150	09/29/1999	METHOD FOR CLEANING AND TREATING A SEMICONDUCTOR WAFER AFTER CHEMICAL MECHANICAL POLISHING	MIKHAYLICH, KATRINA A.
<u>09336401</u>	Not Issued	161	06/18/1999	POST-PLASMA PROCESSING WAFER CLEANING METHOD AND SYSTEM	MIKHAYLICH, KATRINA A.
<u>09329207</u>	<u>6711775</u>	150	06/10/1999	SYSTEM FOR CLEANING A SEMICONDUCTOR WAFER	MIKHAYLICH, KATRINA A.
<u>09322198</u>	<u>6352595</u>	150	05/28/1999	METHOD AND SYSTEM FOR CLEANING A CHEMICAL MECHANICAL POLISHING PAD	MIKHAYLICH, KATRINA A.
<u>09183568</u>	<u>6093254</u>	150	10/30/1998	METHOD OF HF-HF CLEANING	MIKHAYLICH, KATRINA

Inventor Search Completed: No Records to Display.

Search Another: Inventor	Last Name	First Name
	<input type="text" value="MIKHAYLICH"/>	<input type="text" value="KATRINA"/>
	<input type="button" value="Search"/>	

To go back use Back button on your browser toolbar.

Back to [PALM](#) | [ASSIGNMENT](#) | [OASIS](#) | [Home page](#)

D
Sa
D
12Ti
20

PALM INTRANET

Inventor Name Search Result

Your Search was:

Last Name = RAVKIN

First Name = MIKE

Application#	Patent#	Status	Date Filed	Title	Inventor Name 29
<u>60305373</u>	Not Issued	159	07/13/2001	METHODS FOR ANALYZING THE EFFECTIVENESS OF WAFER BACKSIDE CLEANING	RAVKIN, MIKE
<u>10817398</u>	Not Issued	030	04/01/2004	CONTROLS OF AMBIENT ENVIRONMENT DURING WAFER DRYING USING PROXIMITY HEAD	RAVKIN, MIKE
<u>10766733</u>	Not Issued	030	01/27/2004	METHOD AND SYSTEM FOR CLEANING A SEMICONDUCTOR WAFER	RAVKIN, MIKE
<u>10749983</u>	Not Issued	041	12/30/2003	END-POINT DETECTION APPARATUS	RAVKIN, MIKE
<u>10746114</u>	Not Issued	030	12/23/2003	METHOD AND APPARATUS FOR CLEANING SEMICONDUCTOR WAFERS USING COMPRESSED AND/OR PRESSURIZED FOAMS, BUBBLES, AND/OR LIQUIDS	RAVKIN, MIKE

<u>10745219</u>	Not Issued	020	12/22/2003	EDGE DRY MANIFOLD	RAVKIN, MIKE
<u>10662096</u>	<u>6827793</u>	150	09/12/2003	DRIP MANIFOLD FOR UNIFORM CHEMICAL DELIVERY	RAVKIN, MIKE
<u>10611140</u>	Not Issued	030	06/30/2003	METHOD AND APPARATUS FOR CLEANING A SUBSTRATE USING MEGASONIC POWER	RAVKIN, MIKE
<u>10607611</u>	Not Issued	030	06/27/2003	APPARATUS AND METHOD FOR DEPOSITING AND PLANARIZING THIN FILMS OF SEMICONDUCTOR WAFERS	RAVKIN, MIKE
<u>10404270</u>	Not Issued	030	03/31/2003	VERTICAL PROXIMITY PROCESSOR	RAVKIN, MIKE
<u>10309641</u>	<u>6616772</u>	150	12/03/2002	METHODS FOR WAFER PROXIMITY CLEANING AND DRYING	RAVKIN, MIKE
<u>10261839</u>	Not Issued	030	09/30/2002	METHOD AND APPARATUS FOR DRYING SEMICONDUCTOR WAFER SURFACES USING A PLURALITY OF INLETS AND OUTLETS HELD IN CLOSE PROXIMITY TO THE WAFER SURFACES	RAVKIN, MIKE
<u>10234413</u>	Not Issued	061	09/03/2002	SYSTEMS FOR REDUCING PHOTO- ASSISTED CORROSION IN WAFERS DURING CLEANING PROCESSES	RAVKIN, MIKE
<u>10078941</u>	<u>6679763</u>	150	02/20/2002	APPARATUS AND METHOD FOR QUALIFYING A CHEMICAL	RAVKIN, MIKE

				MECHANICAL PLANARIZATION PROCESS	
<u>10052769</u>	<u>6726530</u>	150	01/17/2002	END-POINT DETECTION SYSTEM FOR CHEMICAL MECHANICAL POLISHING APPLICATIONS	RAVKIN, MIKE
<u>10013211</u>	Not Issued	093	12/07/2001	METHOD FOR CONTROLLING GALVANIC CORROSION EFFECTS ON A SINGLE-WAFER CLEANING SYSTEM	RAVKIN, MIKE
<u>09863781</u>	<u>6543084</u>	150	05/22/2001	WAFER SCRUBBING BRUSH CORE	RAVKIN, MIKE
<u>09752697</u>	<u>6611326</u>	150	12/27/2000	SYSTEM AND APPARATUS FOR EVALUATING THE EFFECTIVENESS OF WAFER DRYING OPERATIONS	RAVKIN, MIKE
<u>09752609</u>	<u>6521050</u>	150	12/27/2000	METHODS FOR EVALUATING ADVANCED WAFER DRYING TECHNIQUES	RAVKIN, MIKE
<u>09608522</u>	<u>6435952</u>	150	06/30/2000	APPARATUS AND METHOD FOR QUALIFYING A CHEMICAL MECHANICAL PLANARIZATION PROCESS	RAVKIN, MIKE
<u>09608244</u>	<u>6488040</u>	150	06/30/2000	CAPILLARY PROXIMITY HEADS FOR SINGLE WAFER CLEANING AND DRYING	RAVKIN, MIKE
<u>09608242</u>	<u>6375540</u>	150	06/30/2000	END-POINT DETECTION SYSTEM FOR CHEMICAL MECHANICAL POLISHING	RAVKIN, MIKE

				APPLICATIONS	
<u>09607895</u>	<u>6361414</u>	150	06/30/2000	APPARATUS AND METHOD FOR CONDITIONING A FIXED ABRASIVE POLISHING PAD IN A CHEMICAL MECHANICAL PLANARIZATION PROCESS	RAVKIN, MIKE
<u>09538865</u>	<u>6622335</u>	150	03/29/2000	DRIP MANIFOLD FOR UNIFORM CHEMICAL DELIVERY	RAVKIN, MIKE
<u>09537913</u>	<u>6594847</u>	150	03/28/2000	SINGLE WAFER RESIDUE, THIN FILM REMOVAL AND CLEAN	RAVKIN, MIKE
<u>09454698</u>	<u>6240588</u>	150	12/03/1999	WAFER SCRUBBING BRUSH CORE	RAVKIN, MIKE
<u>09408281</u>	<u>6537381</u>	150	09/29/1999	METHOD FOR CLEANING AND TREATING A SEMICONDUCTOR WAFER AFTER CHEMICAL MECHANICAL POLISHING	RAVKIN, MIKE
<u>09408001</u>	Not Issued	161	09/29/1999	METHOD AND SYSTEM FOR REDUCING PHOTO-ASSISTED CORROSION IN WAFERS DURING CLEANING PROCESSES	RAVKIN, MIKE
<u>09329207</u>	<u>6711775</u>	150	06/10/1999	SYSTEM FOR CLEANING A SEMICONDUCTOR WAFER	RAVKIN, MIKE

Inventor Search Completed: No Records to Display.

Search Another:
Inventor

Last Name

RAVKIN

First Name

MIKE

Search

To go back use Back button on your browser toolbar.

Back to [PALM](#) | [ASSIGNMENT](#) | [OASIS](#) | Home page

D
Sa
D
12

PALM INTRANET

Ti
20**Inventor Name Search Result**

Your Search was:

Last Name = ANDERSON

First Name = DON

Application#	Patent#	Status	Date Filed	Title	Inventor Name 51
<u>60575479</u>	Not Issued	020	05/28/2004	WORKBOAT FOR INSTALLING AND REMOVING BOATLIFTS	ANDERSON, DONALD L.
<u>60537435</u>	Not Issued	020	01/16/2004	UNIVERSAL RACK MOUNTING CONNECTOR AND ASSEMBLY	ANDERSON, DONALD L.
<u>60526555</u>	Not Issued	159	12/03/2003	CONTROLLING AIRFLOW TO MULTIPLE ENGINE MODULES WITH A SINGLE THROTTLE BODY	ANDERSON, DONALD D.
<u>60493827</u>	Not Issued	159	08/08/2003	VLS GLOBAL POSITIONING SYSTEM INTEGRATOR (VGI) WITH SAASM	ANDERSON, DONALD B.
<u>60493483</u>	Not Issued	159	08/08/2003	THERAPEUTIC GLOVE - A.K.A. - LA STONE MIT	ANDERSON, DONALD
<u>60437314</u>	Not Issued	159	12/30/2002	HIGH SPEED PCIX ROUTING WITH MORE THAN 4 LOADS	ANDERSON, DONALD
<u>60390641</u>	Not Issued	159	06/21/2002	NEWSPAPER HOLDER/RECYCLER	ANDERSON, DON H.

<u>60362711</u>	Not Issued	159	03/08/2002	GENETIC MARKERS AND METHODS FOR IDENTIFYING TOXIN-PRODUCING ORGANISMS	ANDERSON, DONALD M.
<u>60278759</u>	Not Issued	159	03/27/2001	"CLOSE-UP SOUND" WIRELESS HEADSET WITH RADIO	ANDERSON, DONNIE L.
<u>29139089</u>	D459848	150	03/26/2001	SET OF BRUSH TENDERS	ANDERSON, DONALD C.
<u>29125313</u>	Not Issued	167	06/15/2000	REFRIGERATION COMPRESSOR OIL PRESSURE TEST GAUGE	ANDERSON, DONALD F.
<u>10881148</u>	Not Issued	030	06/30/2004	HOT-START NAVIGATION INFORMATION DISTRIBUTION SYSTEM	ANDERSON, DONALD B.
<u>10862671</u>	Not Issued	030	06/07/2004	MULTI-LAYERED FILM WINDOW SYSTEM	ANDERSON, DONALD
<u>10842275</u>	Not Issued	030	05/10/2004	EXHAUST COOLING TEMPERATURE MONITOR FOR A MARINE PROPULSION SYSTEM	ANDERSON, DONALD W.
<u>10811740</u>	Not Issued	030	03/29/2004	TANDEM CONNECTION SYSTEM FOR TWO OR MORE MARINE PROPULSION DEVICES	ANDERSON, DONALD
<u>10799911</u>	Not Issued	030	03/12/2004	EXHAUST SYSTEM CATALYST ASSEMBLY FOR A DUAL CRANKSHAFT ENGINE	ANDERSON, DONALD D.
<u>10797693</u>	6824628	150	03/09/2004	METHOD AND APPARATUS FOR AUTOMATED LOCATION MARKING	ANDERSON, DONALD A.

<u>10774808</u>	Not Issued	092	02/09/2004	COMPACT JACK PLATE WITH IMPROVED ACCESS TO HYDRAULIC COMPONENTS	ANDERSON, DONALD
<u>10766733</u>	Not Issued	030	01/27/2004	METHOD AND SYSTEM FOR CLEANING A SEMICONDUCTOR WAFER	ANDERSON, DON E.
<u>10758310</u>	Not Issued	030	01/15/2004	POSITIVE CRANKCASE VENTILATION IN AN ENGINE HAVING A CYCLICALLY VARYING CRANKCASE VOLUME	ANDERSON, DONALD D.
<u>10750867</u>	Not Issued	041	01/05/2004	CONTACT SLIDER WITH INCREASED LINEAR TRAVEL	ANDERSON, DONALD G.
<u>10738674</u>	Not Issued	030	12/17/2003	CONTROLLING AIRFLOW TO MULTIPLE ENGINE MODULES WITH A SINGLE THROTTLE BODY	ANDERSON, DONALD D.
<u>10717030</u>	Not Issued	030	11/18/2003	METHOD OF TRANSFERRING LARGE UNCURED COMPOSITE LAMINATES	ANDERSON, DONALD A.
<u>10712542</u>	Not Issued	061	11/13/2003	INTEGRAL TILT LOCK MECHANISM FOR AN OUTBOARD MOTOR	ANDERSON, DONALD
<u>10693661</u>	Not Issued	093	10/24/2003	APPARATUS FOR CREATING A PATHWAY IN AN ANIMAL AND METHODS THEREFOR	ANDERSON, DONALD E.
<u>10693660</u>	Not Issued	041	10/24/2003	METHOD AND APPARATUS FOR CREATING A	ANDERSON, DONALD E.

				PATHWAY IN AN ANIMAL	
<u>10690930</u>	Not Issued	020	10/22/2003	VEHICLE FRAME WITH INTEGRATED HIGH PRESSURE FUEL TANK	ANDERSON, DONALD D.
<u>10662096</u>	<u>6827793</u>	150	09/12/2003	DRIP MANIFOLD FOR UNIFORM CHEMICAL DELIVERY	ANDERSON, DON E.
<u>10640188</u>	Not Issued	041	08/13/2003	FORMING APPARATUS AND METHOD	ANDERSON, DONALD A.
<u>10611303</u>	<u>6823532</u>	150	10/20/2003	MALODOR CONTROL SYSTEMS FOR TOILETS	ANDERSON, DONALD C.
<u>10341774</u>	Not Issued	161	01/14/2003	COMPOSITE EXHAUST MANIFOLD	ANDERSON, DONALD D.
<u>10304524</u>	<u>6662750</u>	150	11/26/2002	METHOD AND APPARATUS FOR CREATING A PATHWAY IN AN ANIMAL	ANDERSON, DONALD E.
<u>10295008</u>	Not Issued	161	11/14/2002	APPARATUS FOR CREATING A PATHWAY IN AN ANIMAL AND METHODS THEREFOR	ANDERSON, DONALD E.
<u>10251945</u>	Not Issued	041	09/20/2002	REGENERATIVE SELF PROPELLED VEHICLES	ANDERSON, DONALD C.
<u>10161575</u>	<u>6526917</u>	150	05/31/2002	METHOD AND APPARATUS FOR CREATING A PATHWAY IN AN ANIMAL	ANDERSON, DONALD E.
<u>10118852</u>	Not Issued	160	04/10/2002	WIRELESS HEADSET WITH RADIO	ANDERSON, DONNIE L.
<u>10052949</u>	Not Issued	094	01/17/2002	DENTAL CARE PET FOOD	ANDERSON, DONNA ELIZABETH
<u>10037941</u>	Not	041	01/03/2002	DENTAL DIET FOR	ANDERSON,

	Issued			REDUCING TARTAR	DONNA ELIZABETH
<u>10012609</u>	<u>6736180</u>	150	10/30/2001	METHOD AND APPARATUS FOR AUTOMATED LOCATION MARKING	ANDERSON, DONALD A.
<u>09936672</u>	Not Issued	071	01/23/2002	DENTAL DIET FOR REDUCING TARTAR	ANDERSON, DONNA ELIZABETH
<u>09930526</u>	<u>6487486</u>	150	08/14/2001	AUTOMATIC DIFFERENTIAL CONTROL LOGIC	ANDERSON, DONALD D.
<u>09863781</u>	<u>6543084</u>	150	05/22/2001	WAFER SCRUBBING BRUSH CORE	ANDERSON, DONALD E.
<u>09827813</u>	Not Issued	200	04/06/2001	GOLF CLUB HEAD	ANDERSON, DONALD A.
<u>09770414</u>	<u>6568976</u>	150	01/29/2001	WATER FLOATATION CUSHION WITH DEPLOYABLE TETHER	ANDERSON, DON
<u>09679470</u>	<u>6811189</u>	150	10/04/2000	CORROSION SEAL FOR THREADED CONNECTIONS	ANDERSON, DONNA S.
<u>09651599</u>	<u>6557724</u>	150	08/30/2000	VERTICAL CONVEYOR	ANDERSON, DONALD L
<u>09651081</u>	Not Issued	161	08/30/2000	VERTICAL CONVEYOR	ANDERSON, DONALD L.
<u>09607895</u>	<u>6361414</u>	150	06/30/2000	APPARATUS AND METHOD FOR CONDITIONING A FIXED ABRASIVE POLISHING PAD IN A CHEMICAL MECHANICAL PLANARIZATION PROCESS	ANDERSON, DON E.
<u>09538865</u>	<u>6622335</u>	150	03/29/2000	DRIP MANIFOLD FOR UNIFORM CHEMICAL DELIVERY	ANDERSON, DON E.
<u>09483328</u>	Not Issued	161	01/14/2000	DENTAL DIET FOR REDUCING TARTAR	ANDERSON, DONNA ELIZABETH

<u>09450299</u>	Not Issued	161	11/29/1999	GOLF CLUB HEAD	ANDERSON, DONALD A.
-----------------	---------------	-----	------------	----------------	------------------------

[Search and Display More Records.](#)

Search Another: Inventor	Last Name	First Name
	<input type="text" value="ANDERSON"/>	<input type="text" value="DON"/>
	<input type="button" value="Search"/>	

To go back use Back button on your browser toolbar.

Back to [PALM](#) | [ASSIGNMENT](#) | [OASIS](#) | [Home page](#)

DERWENT-ACC-NO: 1997-235713

DERWENT-WEEK: 200418

COPYRIGHT 2004 DERWENT INFORMATION LTD

TITLE: Substrate cleaning system delivers solution
through
semiconductor brush - used to scrub substrate, such as
control of pH wafer, for uniform distribution and greater
without large amounts of chemicals.

INVENTOR: DELARIOS, J M; GARDNER, D G ; RAVKIN, M ; DE LARIOS, J M

PATENT-ASSIGNEE: LAM RES CORP[LAMRN] , ONTRAK SYSTEMS INC[ONTRN]

PRIORITY-DATA: 1995US-0542531 (October 13, 1995) , 1997US-0932292
(September
17, 1997)

PATENT-FAMILY:

PUB-NO	PUB-DATE	LANGUAGE
PAGES MAIN-IPC		
DE 69631258 E	February 5, 2004	N/A
000 B08B 001/04		
WO 9713590 A1	April 17, 1997	E
022 B08B 001/00		
AU 9672645 A	April 30, 1997	N/A
000 N/A		
US 5806126 A	September 15, 1998	N/A
000 B08B 007/00		
EP 914216 A1	May 12, 1999	E
000 N/A		
KR 99064221 A	July 26, 1999	N/A
000 B08B 001/00		
EP 1046433 A1	October 25, 2000	E
000 B08B 001/04		
EP 914216 B1	March 20, 2002	E
000 B08B 001/00		
DE 69620037 E	April 25, 2002	N/A
000 B08B 001/00		
EP 1046433 B1	January 2, 2004	E
000 B08B 001/04		
KR 392828 B	October 17, 2003	N/A
000 C23G 001/00		

DESIGNATED-STATES: AL AM AT AU AZ BA BB BG BR BY CA CH CN CU CZ DE DK
 EE ES FI
 GB GE HU IL IS JP KE KG KP KR KZ LC LK LR LS LT LU LV MD MG MK MN MW
 MX NO NZ
 PL PT RO RU SD SE SG SI SK TJ TM TR TT UA UG US UZ VN AT BE CH DE DK
 EA ES FI
 FR GB GR IE IT KE LS LU MC MW NL OA PT SD SE SZ UG DE FR GB IE IT DE
 FR GB IE
 IT DE FR GB IE IT DE FR GB IE IT

CITED-DOCUMENTS: US 2860354; US 3500490 ; US 4461052

APPLICATION-DATA:

PUB-NO	APPL-DESCRIPTOR	APPL-NO
APPL-DATE		
DE 69631258E	N/A	1996DE-0631258
October 11, 1996		
DE 69631258E	N/A	2000EP-0116480
October 11, 1996		
DE 69631258E	Based on	EP 1046433
N/A		
WO 9713590A1	N/A	<u>1996WO-US16330</u>
October 11, 1996		
AU 9672645A	N/A	1996AU-0072645
October 11, 1996		
AU 9672645A	Based on	WO 9713590
N/A		
US 5806126A	Cont of	1995US-0542531
October 13, 1995		
US 5806126A	N/A	1997US-0932292
September 17, 1997		
EP 914216A1	N/A	1996EP-0934167
October 11, 1996		
EP 914216A1	N/A	<u>1996WO-US16330</u>
October 11, 1996		
EP 914216A1	Based on	WO 9713590
N/A		
KR 99064221A	N/A	<u>1996WO-US16330</u>
October 11, 1996		
KR 99064221A	N/A	1998KR-0702707
April 13, 1998		
KR 99064221A	Based on	WO 9713590
N/A		
EP 1046433A1	Div ex	1996EP-0934167
October 11, 1996		
EP 1046433A1	N/A	2000EP-0116480
October 11, 1996		
EP 1046433A1	Div ex	EP 914216
N/A		
EP 914216B1	N/A	1996EP-0934167

October 11, 1996		
EP 914216B1	N/A	<u>1996WO-US16330</u>
October 11, 1996		
EP 914216B1	Related to	2000EP-0116480
October 11, 1996		
EP 914216B1	Related to	EP 1046433
N/A		
EP 914216B1	Based on	WO 9713590
N/A		
DE 69620037E	N/A	1996DE-0620037
October 11, 1996		
DE 69620037E	N/A	1996EP-0934167
October 11, 1996		
DE 69620037E	N/A	<u>1996WO-US16330</u>
October 11, 1996		
DE 69620037E	Based on	EP 914216
N/A		
DE 69620037E	Based on	WO 9713590
N/A		
EP 1046433B1	Div ex	1996EP-0934167
October 11, 1996		
EP 1046433B1	N/A	2000EP-0116480
October 11, 1996		
EP 1046433B1	Div ex	EP 914216
N/A		
KR 392828B	N/A	<u>1996WO-US16330</u>
October 11, 1996		
KR 392828B	N/A	1998KR-0702707
April 13, 1998		
KR 392828B	Previous Publ.	KR 99064221
N/A		
KR 392828B	Based on	WO 9713590
N/A		

INT-CL (IPC): A46B011/00, A46B013/00 , B08B001/00 , B08B001/04 ,
 B08B003/08 , B08B007/00 , C23G001/00 , C23G001/02 , C23G001/14 ,
 H01L021/00

RELATED-ACC-NO: 1999-119698, 1999-152640 , 2001-069791 , 2002-170714

ABSTRACTED-PUB-NO: EP 914216B

BASIC-ABSTRACT:

In a method of cleaning a substrate, a solution is applied to the
 substrate
 through a brush which also scrubs the substrate. Alternatively, (i)
 the
 substrate is scrubbed with a brush, an HF soln. is applied to the

substrate and
the brush is rinsed; or (ii) the substrate is placed in a scrubber, a
first
scrubbing cycle is carried out at a first station where a first soln
. is
applied to the substrate through the brush, a second scrubbing cycle
is carried
out at a second station using a second soln. and second brush and the
brush is
rinsed. Also claimed is an appts. for carrying out the process.

Pref. a PVA brush is used.

USE - For cleaning a substrate, such as semiconductor wafers.

ADVANTAGE - The system may be used in existing scrubbers and applies
the
solution in a manner that allows uniform distribution of the solution
and
greater control over the pH profile but does not use large amounts of
chemicals.

ABSTRACTED-PUB-NO: US 5806126A

EQUIVALENT-ABSTRACTS:

In a method of cleaning a substrate, a solution is applied to the
substrate
through a brush which also scrubs the substrate. Alternatively, (i)
the
substrate is scrubbed with a brush, an HF soln. is applied to the
substrate and
the brush is rinsed; or (ii) the substrate is placed in a scrubber, a
first
scrubbing cycle is carried out at a first station where a first soln
. is
applied to the substrate through the brush, a second scrubbing cycle
is carried
out at a second station using a second soln. and second brush and the
brush is
rinsed. Also claimed is an appts. for carrying out the process.

Pref. a PVA brush is used.

USE - For cleaning a substrate, such as semiconductor wafers.

ADVANTAGE - The system may be used in existing scrubbers and applies
the
solution in a manner that allows uniform distribution of the solution
and

greater control over the pH profile but does not use large amounts of chemicals.

In a method of cleaning a substrate, a solution is applied to the substrate through a brush which also scrubs the substrate. Alternatively, (i) the substrate is scrubbed with a brush, an HF soln. is applied to the substrate and the brush is rinsed; or (ii) the substrate is placed in a scrubber, a first scrubbing cycle is carried out at a first station where a first soln. is applied to the substrate through the brush, a second scrubbing cycle is carried out at a second station using a second soln. and second brush and the brush is rinsed. Also claimed is an appts. for carrying out the process.

Pref. a PVA brush is used.

USE - For cleaning a substrate, such as semiconductor wafers.

ADVANTAGE - The system may be used in existing scrubbers and applies the solution in a manner that allows uniform distribution of the solution and greater control over the pH profile but does not use large amounts of chemicals.

WO 9713590A

CHOSEN-DRAWING: Dwg.0/3

TITLE-TERMS: SUBSTRATE CLEAN SYSTEM DELIVER SOLUTION THROUGH BRUSH SCRUB

SUBSTRATE SEMICONDUCTOR WAFER UNIFORM DISTRIBUTE GREATER
CONTROL PH
AMOUNT CHEMICAL

DERWENT-CLASS: A88 L03 P24 P43 U11

CPI-CODES: A11-C; A12-H; L04-C09;

EPI-CODES: U11-C06A1B;

UNLINKED-DERWENT-REGISTRY-NUMBERS: 1534U; 1712U

ENHANCED-POLYMER-INDEXING:
Polymer Index [1.1]

018 ; P1707 P1694 D01

Polymer Index [1.2]

018 ; ND01 ; Q9999 Q6815 ; Q9999 Q7034*R ; K9416 ; Q9999 Q7476
Q7330

SECONDARY-ACC-NO:

CPI Secondary Accession Numbers: C1997-075580

Non-CPI Secondary Accession Numbers: N1997-194919